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Tailoring photodetection performance of self-powered Ga₂O₃ UV solar-blind photodetectors through asymmetric electrodes

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Self-powered solar-blind UV detectors have become an increasingly critical role in the sustainable development of photodetectors with low energy consumption. In this work, the design of electrode structures, including the asymmetric-size structure and the asymmetric-material structure, was proposed to achieve the self-powered photodetection function for solar-blind UV a-Ga₂O₃ based photodetectors with the metal-semiconductor-metal (MSM) structure. The results indicate that the Au/Ti/Ga₂O₃/Ti/Au photodetector with the asymmetric-electrode-size hosts photodetection performances of responsivity (*R*), external quantum efficiency (*EQE*) and detectivity (*D*^{*}) of 0.149 mA/W, 0.07% and 3.1×10⁹ cm Hz^{1/2} W⁻¹ @0 V, respectively. The asymmetric-electrode-material photodetectors with Au/Ti/Ga₂O₃/GZO and Au/Ti/Ga₂O₃/Au structures possess photodetection performances of *R*, *EQE*, *D*^{*} of 0.591 mA/W, 0.29%, 2.9×10⁹ cm Hz^{1/2} W⁻¹, and 0.148 mA/W, 0.07%, 7.8×10⁸ cm Hz^{1/2} W⁻¹ @0 V, respectively. The electrodes with the asymmetric-size structure and the asymmetric-material structure result in difference Schottky barrier heights in interfaces of electrodes and films, which are in favor of realizing the self-powered performance. The self-powered solar-blind UV a-Ga₂O₃ based photodetectors have fast photo-response speed, high-stability and high-repeatability. These findings provide a promising and facile route to fabricate a-Ga₂O₃ self-powered solar-blind UV photodetectors with high photodetection.

Introduction

Solar-blind ultraviolet (UV) photodetectors, which work in the wavelength region of 200~280 nm, have attracted an increasing attention in many application fields, such as ultraviolet communication, ultraviolet imaging, biology, and missile warning system due to its excellent properties including high sensitivity, high signal-to-noise ratio, small size, and light weight¹⁻¹⁰. By using the internal built-in electric field in a junction device, self-powered solar-blind UV photodetectors can be realized since its electron-hole pairs were independently separated by the built-in electric field¹¹⁻¹⁶. Nowadays, the smart photodetectors with the merits of high intelligence, high integration, miniaturized size, and low energy cost are in demand, which is favour in the sustainable development and practical application¹⁷. Compared to other semiconductor materials, such as silicon (Si), diamond, GaN, MgZnO, AlGaIn, etc., the Ga₂O₃ material is an ideal candidate for fabricating solar blind photodetectors due to its suitable band-gap (~4.9 eV), facile preparation process, and low cost¹⁸⁻²¹. Up to now, various kinds of self-powered UV solar-blind photodetectors based on Ga₂O₃ materials grown on different substrates have been reported, which include the device structures of p-n junctions, heterojunctions and Schottky junctions. Guo et al.²² investigated the photodetection performance of a p-n junction detector based on the structure of GaN/Sn:Ga₂O₃ on sapphire substrate. It exhibited a high

performance of responsivity, *R* up to 3.05 A/W under the 254 nm illumination @ 0 V. Wang et al.²³ fabricated an all-oxide NiO/Ga₂O₃ solar-blind photodetector with the p-n junction structure, which hosts a responsivity of 57 μA/W @ 0 V when exposed to a 254 nm light source. He et al.²⁴ manufactured a α-Ga₂O₃/Cu₂O p-n junction for a UV photodetector, which exhibited a *R* of 0.42 mA/W under 254 nm UV light @ 0 V. Zhao et al.¹⁵ fabricated a single ZnO-Ga₂O₃ self-powered photodetector with a core-shell heterostructure with the responsivity of 9.7 mA/W under 251 nm UV light @ 0 V. Alternatively, Chen et al.¹⁶ reported that the Au/β-Ga₂O₃ nanowire array with a Schottky junction structure exhibited high response speed. Zhi et al.²⁵ reported a planar Au/β-Ga₂O₃ solar blind photodetector with a Schottky junction structure, which displayed a *R* of 0.4 mA/W and a fast response time (τ_d=50 ms). Nevertheless, the preparation process of crystalline Ga₂O₃ materials and the doping of Ga₂O₃ materials need high growth temperatures and are limited to certain substrates.

Compared with the vertical structure devices including p-n junctions, heterojunctions and Schottky junctions, the planar asymmetric photodetector based on the Schottky junction with metal-semiconductors-metal (MSM) topography has advantages of simple fabrication process, low cost, and high collection efficiency of carriers^{26, 27}. The self-power characteristics of solar blind photodetectors can be realized by adjusting electrode sizes and electrode materials on MSM device structures. In our previous work, we fabricated β-Ga₂O₃ and amorphous Ga₂O₃ (a-Ga₂O₃) based photodetectors^{28, 29}. The fabrication process of a-Ga₂O₃ through the RF sputtering system is facile, which is in favor of the large-area scale fabrication and the batch in production. Up to now, few reports focus on self-powered MSM UV solar-blind photodetectors based on a-Ga₂O₃ materials. In this work, we fabricated MSM solar-blind photodetectors based on a-Ga₂O₃ films grown on Si substrates by tailoring electrode sizes and electrodes materials, respectively. The Ga doped ZnO (GZO) material has excellent transparency and conductivity, which exhibits a bright potential in regarding as the electrode for the Ga₂O₃-based photodetector. The UV solar-blind

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photodetectors based on the asymmetric electrode size (Au/Ti/Ga₂O₃/Ti/Au) and the asymmetric electrode material (Au/Ti/Ga₂O₃/GaZnO (GZO) and Au/Ti/Ga₂O₃/Au) show good response to 254 nm UV illumination at 0 V bias voltage. This work demonstrates an effective approach for realizing the self-powered detection performance of a-Ga₂O₃ based photodetectors, showing a promising prospective to make the miniaturized and high-integrated UV solar-blind photodetectors with other semiconductor devices for the practical applications.

Results and discussion

Figure 1(a) displays a XRD pattern of a typical Ga₂O₃ film grown on Si substrate at RT. There is no existence of diffraction peak associated with the crystalline Ga₂O₃ film except for those of the Si substrate, which indicates that the as-grown Ga₂O₃ film is amorphous structure. To investigate the surface property of Ga₂O₃ film, we conducted the AFM test on 2 μm×2 μm area of the Ga₂O₃ film, as shown in Fig. 1(b). The surface exhibits uniform distribution of grains with the root mean square (RMS) of around 7.325 nm. Fig. 1(c-d) exhibit the X-ray photoelectron spectroscopy (XPS) results. It indicates two peaks appear around 1118.4 eV and 1145.5 eV, which corresponds to Ga 2p_{3/2} and Ga 2p_{1/2}, respectively. The O 1s core-level spectrum is fitted into two components: one peak of O_I (around 530.8 eV) and the other peak of O_{II} (around 531.8 eV). The later peak originates from O²⁻ ions in oxygen-deficient regions^{5, 30}. The peak area represents the proportion of the corresponding component. In Fig. 1(d), the peak area of O_{II} is larger than that of O_I, indicating that there are many oxygen vacancies existed in the Ga₂O₃ film. Furthermore, the ratio of O/Ga is calculated as 0.818 according to the peak intensities of Ga 2p_{3/2} and O 1s while the theoretical ratio of O/Ga is 1.5. It further confirms that there are high oxygen concentrations in a-Ga₂O₃ films. These results agree with the findings of other researches^{31, 32}.

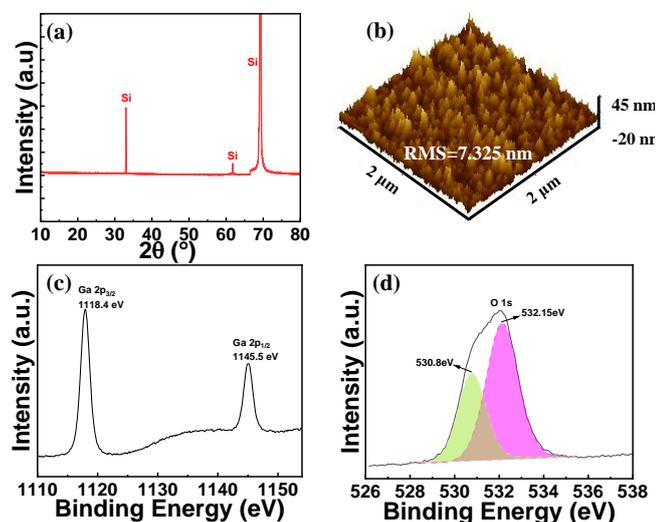


Fig. 1. (a) XRD spectrum, (b) AFM image and XPS spectrum, (c) Ga 2p, (d) O 1s of a Ga₂O₃ thin film grown on Si substrate at RT.

The *I*-*V* characteristics of a-Ga₂O₃-based photodetectors with the symmetric-electrode-size and the asymmetric-electrode-size were measured through the Keithley 4200/SCS facility. Fig. 2(a) and (c) schematically show the photodetection measurement setup of these two kinds of photodetectors. The dark-current, *I_d* and photocurrent, *I_p* of the photodetector was measured in the dark condition and under the 254 nm UV light illumination with the intensity of 120 μW/cm², respectively. As shown in Fig. 2(b) and (d), the dependences of *I_d* on the applying voltage of the symmetric-electrode-size

detector have highly symmetrical characteristic. The *I_d* of the a-Ga₂O₃-based photodetector with the symmetric-electrode-size structure is almost equal to *I_p* at 0 V bias, which displays it exhibits no response to the 254 nm UV light illumination without an external power supply. This result is similar to other works³³⁻³⁵. However, the *I_p* of the a-Ga₂O₃-based photodetector with the asymmetric-electrode-size structure is higher than *I_d* at 0 V bias, which demonstrates this detector realizes a photo-response to the 254 nm UV light illumination without an external power supply. The responsivity (*R*), external quantum efficiency (*EQE*), and detectivity (*D**) are critical parameters to evaluate the photodetection performance of photodetectors. These parameters can be expressed as follows³⁶:

$$R = \frac{I_p - I_d}{P} \quad (1)$$

$$EQE = \frac{hc}{e\lambda} R \quad (2)$$

Wherein *P* is the light power intensity, *h* is the Planck's constant, *c* is the speed of light, *e* is the electronic charge, and *λ* is the wavelength of incident light. The detectivity *D** of a photodetector is used to evaluate the noise, as defined to be³⁷⁻⁴⁰

$$D^* = \frac{R(\Delta f)^{1/2}}{I_n} \quad (3)$$

where *R* is the responsivity of photodetector. *A* is the effective illumination area of detector, *Δf* is the bandwidth, and *I_n* is the current noise mainly caused by carrier generation and recombination processes. There are three main contributions to the noise that limits *D**, including dark-current-induced shot noise, Johnson-Nyquist noise, and thermal fluctuation "flicker" noise. If, as expected, the shot noise from the dark current is the major contribution. Thus, the detectivity can be simplified as^{37, 38}

$$D^* = R \sqrt{\frac{A}{2eI_d}} \quad (4)$$

Based on these above equations, the *R*, *EQE*, and *D** were calculated as shown in table 1. At 0 V bias, the *R*, *EQE* and *D** are 0.149 mA/W, 0.07% and 3.1×10⁹, respectively. Fig. 2(e) shows the transient response of the a-Ga₂O₃-based photodetector with the asymmetric-electrode-size structure. It depicts that the *I_p* intensively increases to a stable value with the UV light turn-on and rapidly decreases with the UV light turn-off. In addition, after several measurement cycles, the photodetection performance of this photodetector shows weak change, indicating a good stability. Fig. 2(f) is the enlarged view of one cycle for the transient response test. It exhibits that the rise time (*τ_r*, the time for the current increasing from 10% to 90% of the maximum photocurrent) is 0.759 s and the decay time (*τ_d*, the time for the current decreasing from 90% to 10% of the maximum photocurrent) is 0.451 s. Besides, the a-Ga₂O₃-based photodetector with the asymmetric-electrode-size structure has the good stability of photodetection performance as kept in atmosphere for two months (Fig. S1 (a), Supplementary data).

Table 1. Photodetection performance of the a-Ga₂O₃-based photodetector with the asymmetric-electrode-size structure

Voltage (V)	<i>R</i> (mA/W)	<i>EQE</i> (%)	<i>D*</i> (cm Hz ^{1/2} W ⁻¹)	<i>τ_r</i> / <i>τ_d</i> (s)
0	0.149	0.07	3.1×10 ⁹	0.759/0.451

Figure 3(a-c) show the energy band diagrams of the a-Ga₂O₃-based photodetector with the symmetric electrode structure in the dark condition and under the 254 nm UV light illumination at 0 V bias. The thermionic emissions expressed by Eq. (5) was used to calculate the height of the Schottky barrier height⁴¹⁻⁴⁴.

$$J_s = A^* T^2 \exp(-q\phi_B/kT) \quad (5)$$

Where k is Boltzmann's constant, T is the evaluated temperature, e is the electron charge, J_s is the saturation current density of the device and it can be obtained from the fitting line intercept of $\ln J-V$, which is shown in Fig. S2. A^* is the Richardson constant, which was estimated as 41 A·cm⁻²·K⁻².⁴⁵ According to the calculation, the heights of the Schottky barrier height between Au/Ti electrode and Ga₂O₃ film on both sides are 0.880 eV and 0.879 eV, respectively, indicating the height of the Schottky barriers on both sides are almost equal. As shown in Fig. 3(a), due to a relatively higher Schottky barrier, few electrons can cross the interface between the Ga₂O₃ film and the electrode, which results in a limited current in the dark condition. Under the 254 nm UV light illumination, the photo electron-hole pairs are generated and moved by a built-in electric field. The photogenerated electrons move away from the contact in the conduction band while the holes move towards the contact interface between the metal electrode and the Ga₂O₃ film, as shown in Fig. 3(b). Many defect states like oxygen deficiency existed at the contact interface can capture photogenerated holes, resulting in a decreased Schottky barrier height⁴⁶⁻⁵¹. Since the electrode width of Au/Ti-1 is larger than that of Au/Ti-2, the number of photogenerated holes captured by Au/Ti-1 is more than that of Au/Ti-2, which leads to a difference Schottky barrier height in the interfaces of Au/Ti-1 electrode and Au/Ti-2 electrode (Fig. 3(c)). In the absence of external power supply, the photogenerated electrons can drift from the Au/Ti-2 side to the Au/Ti-1 side, realizing the self-powered photodetection performance.

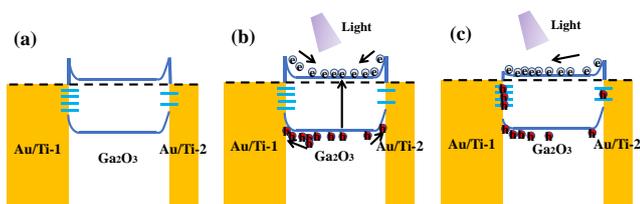


Fig. 3. Schematic diagrams of the energy band of a self-powered photodetector with the asymmetrical electrode size under various conditions: (a) in the dark condition and (b), (c) under the UV light illumination.

As for the photodetector with the Au/Ti/Ga₂O₃/GZO structure (called Au/Ti/Ga₂O₃/GZO photodetector), the positive electrode of the semiconductor analyzer probe is connected to the GZO electrode side and the negative electrode is connected to the Au/Ti side, as shown in Fig. 4(a). As for the photodetector with the Au/Ti/Ga₂O₃/Au structure (called Au/Ti/Ga₂O₃/Au photodetector), the positive electrode of the semiconductor analyzer probe is connected to the Au/Ti electrode side and the negative electrode is connected to the Au side, as shown in Fig. 4(e). Fig. 4(b) and (f) shows the measured plots of $I-V$ characteristics under the dark condition and the light

illumination, it can be seen that the I_d of these two photodetectors is obviously asymmetric, and the I_p are higher than the I_d at 0 V bias, which reveals these photodetectors exhibit good response to the 254 nm UV light illumination in the absence of external power supply. When the UV light source is turned on, the current rises rapidly, and when the UV light source is turned off, the current decreases fast at 0 V bias (Fig. 4(c) and (g)). Moreover, these two photodetectors have high stability and repeatability of photodetection performances. Furthermore, these Au/Ti/Ga₂O₃/GZO and Au/Ti/Ga₂O₃/Au photodetectors host the overshooting performance of I_p with the light turn-on. It means that the I_p suddenly rises to a high value and then gradually decreases to a stable value as the UV light source is turned on. This is attributed that the photogenerated carriers increase instantaneously with the UV light turn-on. Since there is no external power supply, the built-in electric field is not enough to continuously drive the transmission of photogenerated carriers, which results in the carrier accumulation. Thus, the I_p instantaneously increases. Then, the photogenerated carriers are reduced by the recombination until the I_p decays to a stable value^{52, 53}. From Fig. 4(d) and (h), we obtained that τ_r/τ_d of Au/Ti/Ga₂O₃/GZO and Au/Ti/Ga₂O₃/Au photodetectors are 1.060 s/0.342 s and 0.091 s/0.073 s, respectively. According to Eqs. (1), (2) and (3), the R , EQE ,

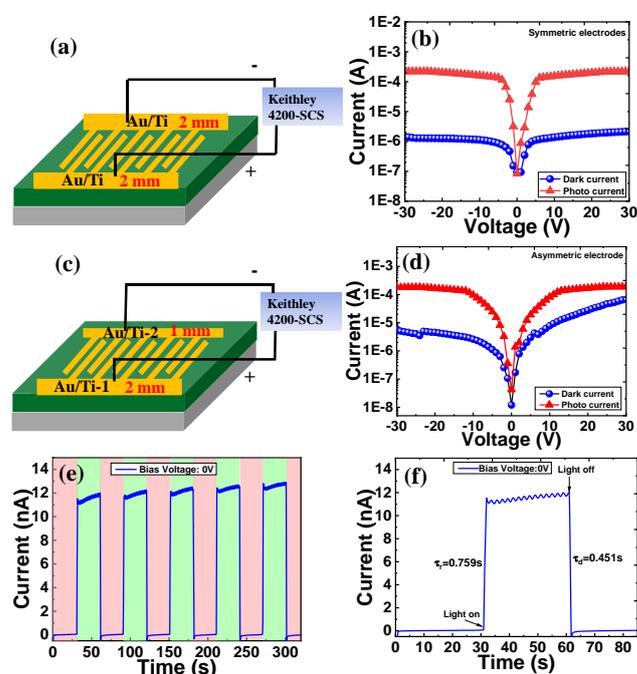


Fig. 2. (a) and (c) Schematic measurement setups of a-Ga₂O₃-based photodetectors with the symmetric electrode structure and the asymmetric electrode structure. (b) and (d) $I-V$ curves of these two photodetectors measured under the dark condition and the 254 nm UV light illumination. (e) Time-dependent photo response of the a-Ga₂O₃-based photodetector with the asymmetric-electrode-size structure @ 0 V, (f) Amplified curve of one test cycle for the rise and decay process @ 0 V.

Table 2. Photodetection performances of a-Ga₂O₃ photodetectors with asymmetric-electrode-material structures

Photodetector type	Voltage (V)	R (mA/W)	EQE (%)	D^* (cm Hz ^{1/2} W ⁻¹)	τ_r/τ_d (s)
Au/Ti/Ga ₂ O ₃ /GZO	0	0.591	0.29	2.9×10 ⁹	1.060/0.342
Au/Ti/Ga ₂ O ₃ /Au	0	0.148	0.07	7.8×10 ⁸	0.091/0.073

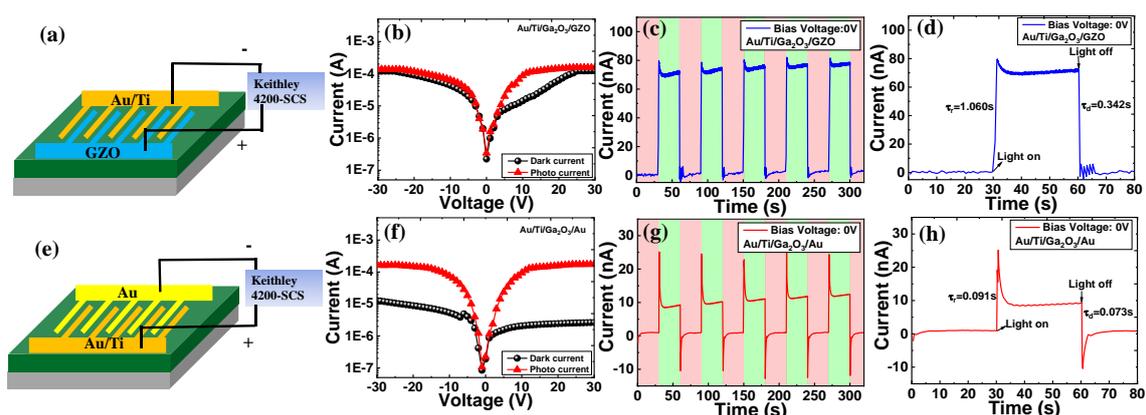


Fig. 4. (a) and (e) Schematic setup diagrams of photodetectors with Au/Ti/Ga₂O₃/GZO and Au/Ti/Ga₂O₃/Au structures. (b) and (f) *I*-*V* plots measured under the dark condition and the 254 nm UV light illumination. (c) and (g) Dependences of *I_p* on the test time. (d) and (h) One-cycle measured curves of the current rise and decay process.

and D^* of Au/Ti/Ga₂O₃/GZO and Au/Ti/Ga₂O₃/Au photodetectors are calculated as 0.591 mA/W, 0.29%, 2.9×10^9 cm Hz^{1/2} W⁻¹ and 0.148 mA/W, 0.07%, 7.8×10^8 cm Hz^{1/2} W⁻¹, respectively, as shown in Table 2. The oxygen vacancies in detectors with asymmetric electrode materials exhibit weak influence on the photodetection performance due to no variation in the electrode size dimension. Alternatively, these Au/Ti/Ga₂O₃/GZO and Au/Ti/Ga₂O₃/Au photodetectors have outstanding stability and repeatability of photodetection performances after placed in atmosphere two months as shown in Fig. S1 (b) and (c).

From Figure. S3 and Eq. (4), the height of Schottky barrier, $q\Phi_{B1}$ between the Ga₂O₃ and the Au/Ti, the $q\Phi_{B2}$ between the Ga₂O₃ and the GZO, and the $q\Phi_{B3}$ between the Ga₂O₃ and the Au are calculated

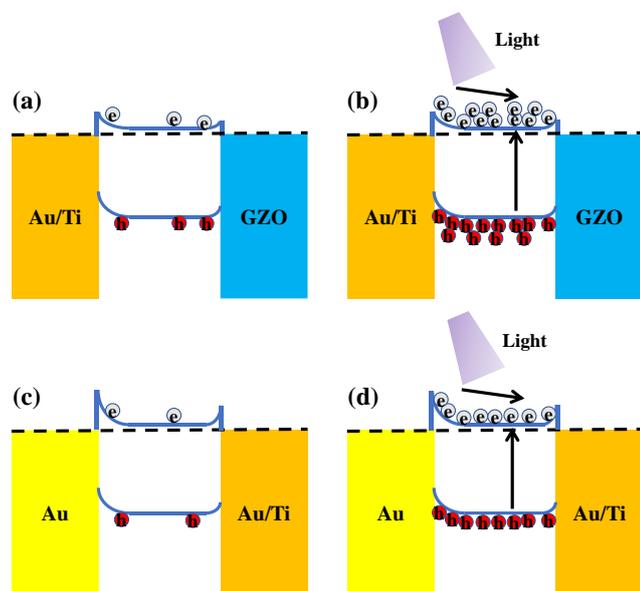


Fig. 5. Schematic diagrams of the energy bands of a-Ga₂O₃ based photodetectors with asymmetrical electrode material structures: (a) in the dark condition and (b) under the UV light illumination for the Au/Ti/Ga₂O₃/GZO photodetector. (c) in the dark condition and (d) under the UV light illumination for the Au/Ti/Ga₂O₃/Au photodetector.

as 0.880 eV, 0.863 eV and 0.898 eV, respectively. As displayed in Fig. 5, few electrons are existed in the dark condition, while under the 254 nm UV light illumination, more electrons are generated. For the Au/Ti/Ga₂O₃/GZO photodetector, as-photogenerated electrons drift from the Au/Ti electrode with the high Schottky barrier height to the GZO electrode with the low Schottky barrier height. For the Au/Ti/Ga₂O₃/Au photodetector, as-photogenerated electrons move from the Au electrode to the Au/Ti electrode. Thus, these photodetectors with asymmetric-electrode-material structures realize the self-powered photodetection performance.

The comparisons of photodetection performances of Ga₂O₃-based self-powered photodetectors are shown in Table 3. The self-powered photodetectors in this work have better responsivity performance. Furthermore, compared to other photodetectors with complex structure based on the crystalline Ga₂O₃, self-powered photodetectors in this work exhibit facile fabrication process, simple structure, which have enormous potential to realize high integration and miniaturization with other electronics for the photodetection applications. In addition, in our future work, the photodetection performance of the self-power a-Ga₂O₃ photodetector can be enhanced through 1) the improvement in quality of the a-Ga₂O₃ thin film; 2) the optimization structures of asymmetric electrodes. Furthermore, the XPS and ultraviolet photoelectron spectroscopy (UPS) studies are critical for getting a better understanding of interfaces from metal electrodes to Ga₂O₃ films. The interface studies between various metals and Ga₂O₃ thin films will be performed in details in our future work, main including influences of various mechanical/chemical surface polishing and the metal kinds on the interface contact. The XPS and UPS techniques will be utilized in details to analyze interface states.

Table 3. Comparisons of photodetection performances of Ga₂O₃-based photodetectors.

Materials	Structure	Growth method	R	τ_r/τ_d	Ref
a-Ga ₂ O ₃	NiO/Ga ₂ O ₃ p-n junction	RF	57 μ A/W@0 V	0.34/3.65 s	23
β -Ga ₂ O ₃	Au/ β -Ga ₂ O ₃ Schottky Junction	-	0.01 mA/W@0 V	$\sim 1 \times 10^{-6}/\sim 6 \times 10^{-5}$ s	16
β -Ga ₂ O ₃	β -Ga ₂ O ₃ /4H-SiC heterojunction	PLD	10.35 mA/W@0 V	11 ms/19 ms	54
ZnO-Ga ₂ O ₃ core-shell	ZnO-Ga ₂ O ₃ heterojunction	One-step CVD	9.7 mA/W@0 V	100 μ s/900 μ s	15
Doped β -Ga ₂ O ₃	VO _x /Ga ₂ O ₃ heterojunction	MOCVD	28.9 mA/W@0 V	57 ms/74 ms	55
a-Ga ₂ O ₃	Au/Ti/Ga ₂ O ₃ /Ti/Au MSM	RF	0.149 mA/W@0 V	0.759 s/0.451 s	This work
a-Ga ₂ O ₃	Au/Ti/Ga ₂ O ₃ /GZO MSM	RF	0.591 mA/W@0 V	1.060 s/0.342 s	This work
a-Ga ₂ O ₃	Au/Ti/Ga ₂ O ₃ /Au MSM	RF	0.148 mA/W@0 V	0.091 s/0.073 s	This work
β -Ga ₂ O ₃	Ni/Au/ β -Ga ₂ O ₃ /Ti/Au diamond/ β -Ga ₂ O ₃ heterojunction	MBE	1.4 mA/W@0 V	1.1 s/0.3 s	56
β -Ga ₂ O ₃	CuMO ₂ /Ga ₂ O ₃ pn heterojunction	PECVD	0.2 mA/W@0 V	-	57
β -Ga ₂ O ₃	CuMO ₂ /Ga ₂ O ₃ pn heterojunction	MOCVD	0.025 mA/W@0 V	0.26 s/0.14 s	58
α -Ga ₂ O ₃	Ga ₂ O ₃ -Al ₂ O ₃ nano tree	-	0.174 mA/W@0 V	0.1 s/0.1 s	59

Experimental

High-quality a-Ga₂O₃ films were grown on (100)-Si substrates by using a RF magnetron sputtering system. The growth parameters are as follows: the substrate temperature of room temperature (RT), the sputtering power of 200 W, the work pressure of 20 mTorr, the atmosphere of 100% Ar, the growth duration of 4 h. The thickness of the as-grown a-Ga₂O₃ film is about 400 nm. The substrate temperature was measured through the thermocouple (CuNi), exhibiting a tiny variation in the substrate temperature during the film growth. X-ray diffraction (XRD) test and atomic force microscope (AFM) facilities were utilized to check amorphous properties and measure surface morphologies of the Ga₂O₃ films, respectively. The XPS technique was utilized to observe the oxygen vacancy concentration in a-Ga₂O₃ films. Prior to electrode depositions, Ga₂O₃ films were orderly ultrasonic cleaned in deionized water, acetone, ethanol, and deionized water for 5 minutes, respectively. The electrodes of 20 nm Ti and 80 nm Au were deposited on a-Ga₂O₃ films at a rate of 0.5 Å/s by using an electron beam deposition facility. The electrodes of GZO films were deposited on a-Ga₂O₃ films through a RF magnetron sputtering system. As for an asymmetric-electrode-size detector, the width of one side electrode of Au/Ti-1 was set as 2 mm and the other side electrode of Au/Ti-2 was set as 1 mm. For the comparison of photodetection performance, we also fabricated a detector with a symmetrical electrode size of 2 mm in width. For the fabrication of an asymmetric-electrode-material detector (Au/Ti/Ga₂O₃/GZO), a 100 nm-thick GZO electrode was deposited on one side of a-Ga₂O₃ film. Then, the 20 nm-thick Ti film followed by an 80 nm-thick Au film was deposited on the other side of a-Ga₂O₃ films. In the same way, in

order to fabricate the Au/Ti/Ga₂O₃/Au photodetector, 20 nm Ti and 80 nm Au were deposited as one side of the interdigital electrode. And then, the other side of the Au electrode with a thickness of 100 nm was deposited. The interfinger spacing is the same for all detectors. A Keithley 4200/SCS semiconductor characterization system and a ZF-5 UV light source (120 μ W) were applied to measure the optical detection performance of a-Ga₂O₃ based UV solar-blind detectors. The distance between the light source and the sample is

about 2 cm. In order to avoid the photo-response from the GZO electrode, the wavelength of ZF-5 UV light source of 254 nm is utilized to examine the photodetection performance of detectors.

Conclusions

In summary, the self-powered asymmetric-electrode-size photodetector and asymmetric-electrode-material photodetector based on amorphous Ga₂O₃ films grown on Si substrates were fabricated, respectively. The self-powered photodetection function was realized through the electrode design of asymmetric-size and asymmetric-material. For the asymmetric-electrode-size photodetector, it hosts photodetection performances of *R*, *EQE* and *D** of 0.149 mA/W, 0.07% and 3.1×10^9 @0 V, respectively. The asymmetric-electrode-material photodetectors with the Au/Ti/Ga₂O₃/GZO structure and the Au/Ti/Ga₂O₃/Au structure possess photodetection performances of *R*, *EQE*, *D** of 0.591 mA/W, 0.29%, 2.9×10^9 cm Hz^{1/2} W⁻¹, and 0.148 mA/W, 0.07%, 7.8×10^8 cm Hz^{1/2} W⁻¹ @0 V, respectively. Besides, detectors with asymmetric electrodes including the asymmetric-size structure and the asymmetric-material structure have the fast photo-response speed under the 254 nm UV light illumination without an external energy supply. These results reveal the excellent self-powered photodetection performances of a-Ga₂O₃ based photodetectors with MSM structures are tailored by modulating asymmetric electrodes. This work provides a promising and facile strategy for fabricating self-powered a-Ga₂O₃ based solar-blind UV photodetectors with high photodetection performance.

Conflicts of interest

The authors declare that they have no conflict of interest.

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